

Substitute for form 1449A/PTO			Complete if Known		
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b> (use as many sheets as necessary)			Application Number	10/664,258	
			Filing Date	September 17, 2003	
			First Named Inventor	Masami Urano	
			Art Unit		
			Examiner Name		
Sheet	1	of	2	Attorney Docket Number	96790P441

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. <sup>1</sup>	Document Number	Publication Date or Issue Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code <sup>2</sup> (if known)			
		<del>US-2002/110312</del>	08-15-2002	<del>Yang et al.</del>	
		US-2002/0071169	06-13-2002	Bowers et al.	
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FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. <sup>1</sup>	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T <sup>2</sup>
		Country Code <sup>3</sup> - Number <sup>4</sup> - Kind Code <sup>5</sup> (if known)				
		<del>DE 19712201</del>	<del>10-01-1998</del>	<del>Bodenseewerk Geratetech</del>		
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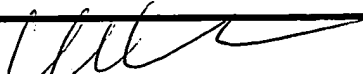
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Based on PTO/SB/08A (03-03) as modified by Blakey, Sotokoff, Taylor & Zelman (w/c) 08/11/2003.

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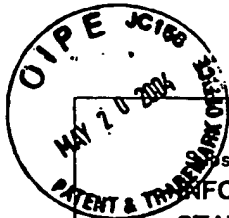
NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T <sup>2</sup>
ML		"Design and fabrication of micromirror supported by electroplated nickel posts", Chung, et al., Elsevier Sequoia S.A., Lausanne, vol. 54, no. 1-3, June 1, 1996, pgs 464-467	
ML		"Infrared Micromirror Array with Large Pixel Size and Large Deflection Angle", B. Wagner, et al., 1997 International Conf. on Solid State Sensors..., June 16-19, 1997, papers no. 3A1.01-4D3.14P, Int'l Conf., vol., 2, June 1997, pgs 75-78	

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		US			
		US			
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FOREIGN PATENT DOCUMENT							
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		Country Code <sup>3</sup>	Number <sup>4</sup>	Kind Code <sup>5</sup> <i>(if known)</i>			
ML		JP	2001-198897	A	07-24-2001	LUCENT TECHNOL INC	ABST
ML		JP	2002-189178	A	07-05-2002	TEXAS INSTR JAPAN LTD	ABST

OTHER PRIOR ART-NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. <sup>1</sup>	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation <sup>6</sup>
ML		Optical Networking: MEMS Mirror Control, ANASOG DEVICES	
ML		Madanagopal et al., Real Time Software Control Of Spring Suspended Micro-Electro-Mechanical (MEM) Devices For Precision Optical Positioning Applications, 2002 International Conference on Optical MEMs 2002, August 2002, pp. 41-42	
ML		Hirao et al., "Circuit Design for High-Speed MEMS Mirror Drive", 2002 IEICE Communications Society Conference, September 11, 2002, pp. 445	
ML		Transistor Technology, the Issue of May 2002, pp. 207 - 212	
ML		"MEMS: Micro Technology, Mega Impact", CIRCUITS & DEVICES, pp. 14-25, March 2001	
ML		Petterson et al., "MOEMS ELECTROSTATIC SCANNING MICROMIRRORS DESIGN AND FABRICATION", Electrochemical Society Proceedings, vol 2002-4, pp. 369- 380	
ML		Sawada et al., "Single Crystalline Mirror Actuated Electrostatically by terraced Electrodes With High-Aspect Ratio Torsion Spring", International Conference on Optical MEMS 2001, September 26, 2001	

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